



# MOOV

Asset No	N/A	Installation date(yy/mm/dd)	N/A
wafer size	200mm	Power off date(yy/mm/dd)	2007-8-1
Software Version	WAVE	Dismantle date(yy/mm/dd)	2007-8-1
SECS/GEM(Y/N)	Y	Production until dismantle(Y/N)	Y

### Chamber/Tank and Key Component Configuration

序号	Vendor/Model	Function/Process	Remark reason and time if any damaged or missing
Heater	VMM-40-101	Middle type/Supply the process thermal	as the package
Transformer	TEL	Middle temp type	as the package
Display screen	TEL	display the process information	as the package
MFC	Area	gas flow control	as the package
Valve	fujikin	gas flow control(open/close)	as the package
Main valve	MKS	pump line open/close control	as the package
Gauge	MKS	pressure control	as the package
System controller	TEL	system/heater/mecha/gas control	as the package
Driver	TEL	mecha control	as the package
CR transfer	TEL	Deliver cassette	as the package
WTR transfer	TEL	Deliver wafer	as the package
Temp controller	TEL	temp control	as the package
Cap	TEL	Rotate/Hold the wafer in the tube	as the package

### Sub system list

Vendor	Model	Serial No	Qty
IN WH, as the package			

### List of missing/Damaged parts/component

序号	Parts No	Parts description	Missing/Damaged time yy/mm/dd	Missing(M)/Damaged(D) reason	Qty
IN WH, as the package					

### Dedicated parts for this tool On-Hand

Parts No	Parts description	In warehouse?(Y/N)
NA	NA	NA

